

IN THE UNITED STATES DESIGNATED OFFICE (DO/US)

In re: Rouviere

Attn: DO/US

International Appl. No.: PCT/FR04/01877

International Filing Date: July 16, 2004

For: METHOD FOR MEASURING PHYSICAL PARAMETERS OF AT LEAST ONE
MICROMETRIC OR NANOMETRIC DIMENSIONAL PHASE IN A COMPOSITE
SYSTEM

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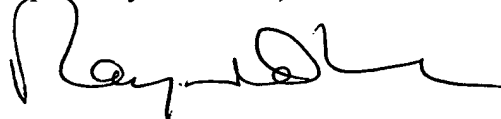
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

The patents listed on the attached PTO-1449 were cited in the International Search Report of corresponding International Application No. PCT/FR04/01877. A copy of the Search Report and documents cited therein are enclosed for the Examiner's convenience.

The Examiner may wish to consider the notations on the Search Report itself regarding the relevance of each item. It is requested that the Examiner consider these references and officially make them of record in accordance with the provisions of 37 C.F.R. § 1.97 and Section 609 of the MPEP. By submitting the listed documents, Applicant in no way makes any admission as to the prior art status of the listed documents, but is instead submitting the listed documents for the sake of full disclosure.

Respectfully submitted,



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Janet F. Sherrill

Substitute for form 1449/PTO (Revised 07/2005) INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	TO BE ASSIGNED
				Filing Date	Concurrently Herewith
				First Named Inventor	Rouviere et al.
				Group Art Unit	
Examiner Name					
Sheet	1	of	1	Attorney Docket Number	033339/306516
OTHER DOCUMENTS					
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.			English Language Translation Attached
	1	PAILLOUX F. et al., "Stress relaxation in $c_{1-c_{//}}$ YBaCuO thin films on MgO substrate studied by LACBED", <i>Thin Solid Films</i> , Elsevier Switzerland, Vol. 368, No. 1, June 1, 2000, pp. 142-146.			YES
	2	LI B et al., "A Study of Residual Strain in a K20.6Ti02W/A1 Composite by Using Convergent Beam Electron Diffraction", <i>Scripta Materialia</i> , Elsevier, New York, NY, Vol. 38, No. 9, April 3, 1998, pp. 1419-1425.			YES
	3	ARMIGLIATO et al., "Application of Convergent Beam Electron Diffraction to Two-Dimensional Strain Mapping in Silicon Devices", <i>Applied Physics Letter</i> , American Institute of Physics, New York, Vol. 82, No. 13, March 31, 2003, pp. 2172-2174.			YES
	4	GAMBETTA F. et al., "Large angle convergent beam electron diffraction strain measurements in high dose helium implanted silicon", <i>Materials Science and Engineering B</i> , Elsevier Sequoia, Lausanne, CH, Vol. 71, No. 1-3, February 2000, pp. 87-91.			YES
	5	WAKAYAMA Y et al., "Strain Distribution Near Si/NiSi ₂ Interface Measured by Convergent Beam Electron Diffraction", <i>Japanese Journal of Applied Physics</i> , Publication Office Japanese Journal of Applied Physics, Tokyo, Japan, Vol. 35, Part 2, No. 12B, December 15, 1996, pp. L1662-L1665.			YES
	6	CLEMENT L et al., "Strain measurements by convergent-beam electron diffraction: the importance of stress relaxation in lamella preparations", <i>Applied Physics Letters AIP USA</i> , Vol. 85, No. 4, July 26, 2004, pp. 651-653.			YES
Examiner Signature					Date Considered

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.